



## > PERFORMANCES OF THE LSPA30uXS DEVELOPER KIT

REFERENCES	UNITS	LSPA30uXS DEV KIT
Notes		
Sensor		MAG
Base		APA30uXS
Stroke	mm	3.4
Stiffness	N/u	0.108
Max Speed	mm/s	30
Typical holding force at rest	N	0.8
Typical actuation force	N	0.2
Sensor resolution	u/M	1.952
Capacitance	u/F	0.052
Height	mm	8.25
Base size	mm	25*34
Mass	gr	8.1
DC Input voltage	V	12
Max Input current (incl. Driver)	A	0.4
Holding consumption	A	0

## > DEDICATED ELECTRONICS' CHARACTERISTICS

The dedicated driver, the "Stepping Piezo Controller" (SPC45) has been built to offer large possibilities to designers, from fast motion setup to completely controlled movement. USB interface, as well as serial port are available to meet every designer's requirements.

## > THE LSPS STAGE

The Linear Stepping Piezo Stage LSPS is based on the Stepping Piezo Actuator's (SPA) principle. It provides both long stroke and micro positioning resolution. A linear rail ensures a flat and straight motion and also protects the system against external forces and vibrations. A linear encoder is included for real time position feedback.

The LSPS is compact, robust, EMC compatible and light weight. The stage can perform more than  $10^6$  cycles.

The piezo stage is driven by a SPC45 controller.

Typical applications are micro positioning, scanning, optical zoom and focus... Customized Stepping Piezo Stages including Rotary Stepping piezo stages can be designed according to customer's requirements.

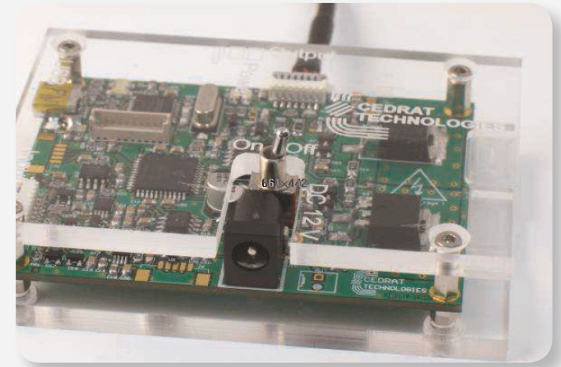


Fig4: Stepping Piezo Controller SPC45.

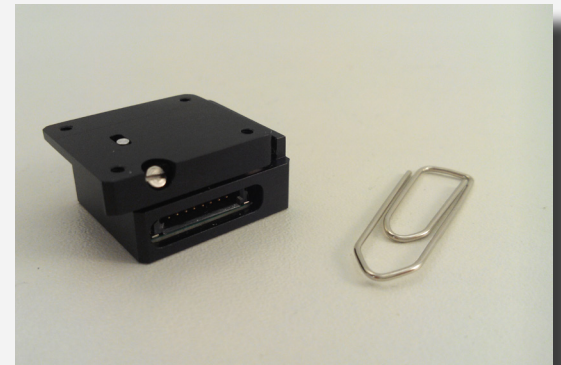


Fig5: Linear Stepping Piezo Stage

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